

Abstract of the Disclosure

SINGAPORE PATENT
GRANTED

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METHOD OF ANALYZING METAL IMPURITIES IN SURFACE
OXIDE FILM OF SEMICONDUCTOR SUBSTRATE

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A method of analyzing metal impurities in a surface oxide film of a semiconductor substrate enables a detection sensitivity of the order of 10^{11} atoms/cm² in a simple technique. This method comprises measuring a quantity of oxide charge resulting from specified metal impurities existing in the surface oxide film formed on the surface of a semiconductor substrate, obtaining a correlation between the quantity of metal impurities and the quantity of oxide charge, and measuring the quantity of metal impurities in the surface oxide film from the quantity of oxide charge of the surface oxide film, based on this correlation. Further, it is possible to obtain the distribution of concentration of the metal impurities in the thermal oxide film on a silicon substrate by obtaining a correlation between a depth of the thermal oxide film and a quantity of oxide charge resulting from the metal impurities in the thermal oxide film and by obtaining a correlation between a quantity of the metal impurities in the thermal oxide film and the quantity of oxide charge resulting therefrom.

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